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TITLE

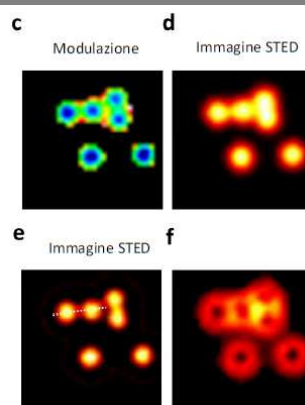
Stimulated emission depletion microscopy method with high spatial resolution

INVENTORS

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DESCRIPTION

The present invention relates to a method for increasing the optical resolution of a stimulated emission depletion microscope or STED (Stimulated Emission Depletion) microscope based on modulating the intensity of a STED beam on an arbitrary time scale during the acquisition of an image and on the analysis of the induced dynamics, without increasing the intensity of the STED beam and in a simple and economic way.



APPLICATIONS

STED Microscopy

KEYWORDS

STED, modulation, depletion, microscopy, optical resolution

BIBLIOGRAPHIC DATA

Metodo di microscopia a deplezione mediante emissione stimolata ad alta risoluzione spaziale

Application Number

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Applicants

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